# Monthly LabAdviser/Process2Share update: 27/5 2015

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| Updated Subject  | Contributor | Link to the updated pages |
| **Sample preparation**Replica molding for sample inspection | **Frederik Stöhr @danchip** | [Characterization/Sample\_preparation](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Sample_preparation) |
| **ICP Metal**Barc etch, new recipe with improved selectivity to KRF resist | **Berit G. Herstrøm @danchip** | [ICP\_Metal\_Etcher/Barc\_Etch](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/ICP_Metal_Etcher/Barc_Etch) |
| **PECVD2**New deposition rate and uniformity values for nitride deposition using 1SiN.New deposition rates and uniformity values for SiO2 deposition using “A test recipe” that will become the new QC recipe soon. | **Berit G. Herstrøm @danchip** | [Deposition\_of\_Silicon\_Nitride\_using\_PECVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_PECVD)[Deposition\_of\_Silicon\_Oxide\_using\_PECVD#SiO2\_Standard.2C\_Low\_Rate](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Oxide/Deposition_of_Silicon_Oxide_using_PECVD#SiO2_Standard.2C_Low_Rate) |
| **IBE**Some examples of blazed gratings etch done in the IBE. | **Berit G. Herstrøm @danchip** | [IBE\_blazed\_gratings](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/IBE%E2%81%84IBSD_Ionfab_300/IBE_blazed_gratings) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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| **Manual for Developer-1**  |
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| **Manual for Developer-2**  |
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| **Manual for Spin coater: RCD8** |
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| **Manual for Balzers sputter coater** |
| **Manual Cammax die bonder**  |
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| **Manual for FilmTek** |